

IN THE CLAIMS

Please amend the claims as follows:

Claim 1 (Currently Amended): A component of a vacuum deposition apparatus, comprising:

a component body; and

a spray deposit coated on a surface of the component body and having surface roughness in which a mean spacing S of tops of local peak of profile is in a range from 50 to 150 μm , a distance from a mean line to a bottom of profile valley line R_v is in a range from 20 to 70 μm , and a distance from a mean line to a top of profile peak line R_p is in a range from 20 to 70 μm , wherein a difference in distance between the top of profile peak line R_p and the bottom of profile valley line R_v ($R_p - R_v$) is in a range from -11 to 6 μm so that a film adhered on the surface of the spray deposit grows with a stable columnar structure.

Claim 2 (Original): The component as set forth in claim 1:

wherein the spray deposit comprises a coat comprising metal of which thermal expansion coefficient is different by $15 \times 10^{-6}/\text{K}$ or less from that of a material deposited by the vacuum deposition apparatus.

Claim 3 (Original): The component as set forth in claim 1:

wherein the spray deposit comprises a coat comprising metal of which thermal expansion coefficient is different by $20 \times 10^{-6}/\text{K}$ or less from that of the component body.

Claim 4 (Previously Presented): The component as set forth in claim 1:

wherein the spray deposit comprises coats of two or more layers of different materials.

Claim 5 (Previously Presented): The component as set forth in claim 4:

wherein the spray deposit comprises a stress relief layer formed on the component body and comprising at least one of Al, Cu, or Ni or alloys of Al, Cu, or Ni, and a thermal

expansion relief layer formed on the stress relief layer and comprising metal of which thermal expansion coefficient is different by $10 \times 10^{-6}/K$ or less from that of a material deposited by the vacuum deposition apparatus.

Claim 6 (Original): The component as set forth in claim 1:

wherein the spray deposit comprises at least one coat selected from an Al base spray deposit of Vickers hardness of Hv 30 or less, a Cu base spray deposit of Vickers hardness of Hv 100 or less, a Ni base spray deposit of Vickers hardness of Hv 200 or less, a Ti base spray deposit of Vickers hardness of Hv 300 or less, a Mo base spray deposit of Vickers hardness of Hv 300 or less, and a W base spray deposit of Vickers hardness of Hv 500 or less.

Claim 7 (Original): The component as set forth in claim 1:

wherein the spray deposit has a thickness in the range from 50 to 500 μm .

Claims 8 -17 (Canceled).

Claim 18 (Original): A vacuum deposition apparatus, comprising:

a vacuum chamber;

a sample holder holding a sample to be deposited and disposed in the vacuum chamber;

a deposition material source disposed in the vacuum chamber facing to the sample holder;

a source holder holding the deposition material source; and a preventive component disposed in the surroundings of the sample holder or the source holder;

wherein at least one selected from the sample holder, the source holder and the preventive component comprises the component for a vacuum deposition apparatus set forth in claim 1.

Claim 19 (Original): The vacuum deposition apparatus as set forth in claim 18:

wherein the spray deposit formed on the surface of the component for a vacuum deposition apparatus comprises a coat containing at least one of metal forming the deposition material source.

Claim 20 (Original): The vacuum deposition apparatus as set forth in claim 18:
wherein the deposition apparatus is a sputtering apparatus.

Claims 21-23 (Canceled).

Claim 24 (Currently Amended): A target apparatus, comprising:
a target body; and
a spray deposit coated on a non-erosion area of the target body and having surface roughness in which a mean spacing S of tops of local peak of profile is in a range from 50 to 150 μm , a distance from a mean line to a bottom of profile valley line R_v is in a range from 20 to 70 μm , and a distance from a mean line to a top of profile peak line R_p is in a range from 20 to 70 μm , wherein a difference in distance between the top of profile peak line R_p and the bottom of profile valley line R_v ($R_p - R_v$) is in a range from -11 to 6 μm so that a film adhered on the surface of the spray deposit grows with a stable columnar structure.

Claim 25 (Currently Amended): A target apparatus, comprising:
a target; and
a backing plate comprising a backing plate body holding the target, and a spray deposit coated on a surface of the backing plate body and having surface roughness in which a mean spacing S of tops of local peak of profile is in a range from 50 to 150 μm , a distance from a mean line to a bottom of profile valley line R_v is in a range from 20 to 70 μm , and a distance from a mean line to a top of profile peak line R_p is in a range from 20 to 70 μm , wherein a difference in distance between the top of profile peak line R_p and the bottom of

profile valley line R_v ($R_p - R_v$) is in a range from -11 to 6 μm so that a film adhered on the surface of the spray deposit grows with a stable columnar structure.

Claims 26-27 (Canceled).

Claim 28 (New): The component as set forth in claim 1:

wherein the mean spacing S of tops of local peak of profile is more than 100 μm .

Claim 29 (New): The component as set forth in claim 1:

wherein the mean spacing S of tops of local peak of profile is 107 μm or more.

Claim 30 (New): The target apparatus as set forth in claim 24:

wherein the mean spacing S of tops of local peak of profile is more than 100 μm .

Claim 31 (New): The target apparatus as set forth in claim 24:

wherein the mean spacing S of tops of local peak of profile is 107 μm or more.

Claim 32 (New): The target apparatus as set forth in claim 25:

wherein the mean spacing S of tops of local peak of profile is more than 100 μm .

Claim 33 (New): The target apparatus as set forth in claim 25:

wherein the mean spacing S of tops of local peak of profile is 107 μm or more.